

**In the abstract**

Page 33, delete the entire abstract paragraph and substitute therefor:

A method of making a dual spin valve sensor includes the steps of forming first and second pinned layer structures, forming antiferromagnetic first and second pinning layers exchange coupled to the first and second pinned layer structures, forming an antiparallel (AP) coupled free layer structure between the first and second pinned layer structures, forming nonmagnetic conductive first and second spacer layers between the AP coupled free layer structure and the first and second pinned layer structures respectively, and a making of the AP coupled free layer structure includes the steps of forming ferromagnetic first, second and third antiparallel (AP) coupled free layers and forming a first antiparallel coupling layer between the first and second AP coupled free layers and a second antiparallel coupling layer between the second and third AP coupled free layers.